

Notice of References Cited

Application/Control No.

09/902,672

Applicant(s)/Patent Under
Reexamination
FUNABASHI, MICHIMASA

Examiner

Lex Malsawma

Art Unit

2825

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*		Document Number	Date	Name	Classification	
		Country Code-Number-Kind Code	MM-YYYY			
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)					
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.